

**NUMERICAL ANALYSIS DURING
ENCAPSULATION PROCESS OF MOLDED
UNDERFILL WITH MULTI FLIP CHIP
PACKAGE**

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MOLDED UNDERFILL WITH MULTI FLIP CHIP PACKAGE**

by

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TABLE OF CONTENTS

	Page
ACKNOWLEDGMENT	ii
TABLE OF CONTENTS	iii
LIST OF TABLES	iv
LIST OF FIGURES	v
LIST OF ABBREVIATIONS	ix
LIST OF SYMBOLS	xi
ABSTRAK	xiii
ABSTRACT	xv
CHAPTER ONE : INTRODUCTION	
1.1 Overview of Integrated Circuit Packaging	1
1.2 Molded Underfill of Flip Chip Package	4
1.3 Numerical Analysis	6
1.4 Problem Statement and Challenges	7
1.5 Aim and Objectives	8
1.6 Scope of the Study	8
1.7 Thesis Outline	9
CHAPTER TWO : LITERATURE REVIEW	
2.1 Integrated Circuit Encapsulation	10
2.1.1 Capillary Underfill	12
2.1.2 Pressurize Underfill	13
2.1.3 No-flow Underfill	14
2.1.4 Molded Underfill	15
2.2 Molded Underfill of Flip Chip Package Technology	15

2.3	Rheology of Epoxy Molding Compound	17
2.3.1	Power Law Model	19
2.3.2	Cross Model	20
2.3.3	Castro Macosko Model	21
2.4	Computational Simulation	24
2.5	Summary	26

CHAPTER THREE : METHODOLOGY

3.1	Introduction	28
3.2	Numerical Method	30
3.2.1	Rheological Model	31
3.3	Simulation Model and Boundary Condition	33
3.3.1	Volume of Fluid Tracking	36
3.3.2	Boundary Condition	36
3.3.3	Measuring Data	37
3.4	Mesh modeling and development	39
3.4.1	Grid Dependency Test	40
3.5	Validation Setup	41
3.5.1	Experimental Setup	41
3.5.2	Simulation Setup	44
3.6	Summary	45

CHAPTER FOUR : RESULTS AND DISCUSSION

4.1	Overview	46
4.2	Experimental and Simulation Validation	46

4.3	Encapsulation Process in Package and Single Multi Flip Chip Package	50
4.3.1	Flow Front Visualization	51
4.3.2	Velocity Profile Distribution	54
4.3.3	Viscosity versus Shear Rate	56
4.3.4	EMC behavior in Single Flip Chip Package	57
4.3.5	Void Formation	61
4.4	Rheological Effect during Encapsulation of Multi Flip Chip Packages	63
4.4.1	Flow Front Visualization	63
4.4.2	Velocity, Shear Rate and Viscosity Profile	66
4.4.3	Viscosity versus Shear Rate	70
4.4.4	Castro Macosko Model	71
4.4.5	Void Formation	78
4.4.6	Prediction of Curing Layer of EMC in the Cavity	80
4.5	Effect of Stacking Design of Multi Flip Chips	84
4.5.1	Flow Front Visualization	84
4.5.2	Velocity, Shear Rate and Viscosity Profile	87
4.5.3	Viscosity versus Shear Rate	90
4.5.4	Void Formation	91
4.5.5	Cross Section of Flow Visualization	94
4.6	Rheological Effect in Stacked Multi Flip Chips Package	95
4.6.1	Flow Front Visualization	95
4.6.2	Velocity, Shear Rate and Viscosity Profile	99
4.6.3	Formation of Weld Line Prediction at Solder Bump	102
4.7	Summary	107

CHAPTER FIVE : CONCLUSIONS

5.1	Conclusions	108
5.2	Recommendations for Future Works	110

REFERENCES	111
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APPENDICES

Appendix A: Cross rheology data of polypropene LyondellBasell 6331 (LB6331) at 200°C from GÖTTFERT Rheograph25.

Appendix B: System Pressure Graph use in Injection Molding Machine Battenfeld TM750/210

LIST OF PUBLICATIONS

LIST OF TABLES

	Page
Table 3.1: Geometry of Flip Chip Package	35
Table 3.2: Hitachi CEL-9200 XU (LF) material properties	37
Table 3.3: The result of grid dependency test	41

LIST OF FIGURES

	Page
Figure 2.1 : Comparison of Cross model and Castro Macosko model flow front (Abdullah et al., 2009)	22
Figure 2.2: Void position at MUF of flip chip package (Khor et al., 2012)	23
Figure 2.3: Comparison of experiment data with model predictions at different temperatures of filling stage for RTM process (Lee & Wei, 2000)	24
Figure 3.1: Flow chart diagram of overview research study	29
Figure 3.2: Package Cavity with Multi Flip Chip Package	34
Figure 3.3: Package Cavity and its dimensions (unit: mm)	34
Figure 3.4: Flip Chip Package	35
Figure 3.5: Solder Bump with dimensions (unit: mm)	35
Table 3.1: Geometry of Flip Chip Package	35
Table 3.2: Hitachi CEL-9200 XU (LF) material properties	37
Figure 3.6: (a) Isometric view (b) Side view of point surface inside the cavity	38
Figure 3.7: (a) Isometric view (b) Side view of line surface inside the cavity	38
Figure 3.8: Meshed model for Cavity Package	39
Figure 3.9: Meshed model for Flip Chip Package	39
Figure 3.10: Rheograph 25 Capillary Rheometer Machine GÖTTFERT	42
Figure 3.11: Injection Molding Machine TM750/210	43
Figure 3.12: Complete injected container	43
Figure 3.13: Container model with dimensions (unit: mm)	44
Figure 3.14: Container meshed model	45

Figure 4.1:	Experimental and simulation flow front profiles of container for 10 MPa inlet pressure	48
Figure 4.2:	Flow front displacement at different time for 10 MPa	49
Figure 4.3:	Viscosity versus shear rate of cross model material between experiment and simulation results	50
Figure 4.4:	Flow front profiles for empty package	52
Figure 4.5:	Flow front profiles for multi flip chip packages	53
Figure 4.6 :	Velocity profile distribution of EMC in empty cavity package	55
Figure 4.7:	Velocity profile distribution of EMC in multi flip chip package	56
Figure 4.8:	Viscosity versus shear rate of EMC between empty cavity and multi flip chip package	57
Figure 4.9:	Temperature versus filling time of EMC in Single Flip Chip	58
Figure 4.10:	Velocity versus filling time of EMC in Single Flip Chip	59
Figure 4.11:	Shear rate versus filling time of EMC in Single Flip Chip	60
Figure 4.12:	Viscosity versus filling time of EMC in Single Flip Chip	61
Figure 4.13:	Void formation in molded underfill of flip chip package (in %)	62
Figure 4.14:	Percentage average volume of void formation in flip chip package	63
Figure 4.15:	Flow visualization of MUF package for different rheology models during encapsulation	65
Figure 4.16:	Flow front displacement of all rheology model	66
Figure 4.17:	Velocity versus Z-direction of Cavity Package	67
Figure 4.18:	Shear rate versus Z-direction of Cavity Package	68
Figure 4.19:	Viscosity versus Z-direction of Cavity Package	69

Figure 4.20:	Viscosity versus shear rate for three different rheology models	71
Figure 4.21:	Flow front in MUF for multi flip chip package using Castro Macosko Model	73
Figure 4.22:	EMC flow front displacement at different filling time for Castro Macosko model	74
Figure 4.23:	Velocity versus Z-direction of Cavity Package	75
Figure 4.24:	Sehar rate versus Z-direction of Cavity Package	76
Figure 4.25:	Viscosity versus Z-direction of Cavity Package	77
Figure 4.26:	Viscosity versus Shear rate of Castro Macosko model	78
Figure 4.27:	Void formation at flip chip package (in %)	79
Figure 4.28:	Percentage average volume of void formation in three different row for Castro Macosko models	80
Figure 4.29:	Velocity profile of EMC in cavity package at different filling Time	81
Figure 4.30:	Temperature contour of EMC in cavity package during Encapsulation	82
Figure 4.31:	Velocity profile of EMC in single flip chip package at different filling time	83
Figure 4.32:	Temperature contour of EMC in single flip chip package during encapsulation	84
Figure 4.33:	Flow visualization of various design of flip chip package during encapsulation process	86
Figure 4.34:	Flow front displacement between different stacking of flip chip package during encapsulation	87
Figure 4.35:	Velocity versus Z-direction of cavity package in different stacking of flip chip package	88
Figure 4.36:	Shear rate versus Z-direction of cavity package in different stacking of flip chip package	89
Figure 4.37:	Viscosity versus Z-direction of cavity package in different stacking of flip chip package	90

Figure 4.38:	Viscosity versus shear rate for various design of flip chip package during encapsulation	91
Figure 4.39:	Void formation for various design of flip chip package	92
Figure 4.40:	Percentage of void formation in three different design of flip chip package	93
Figure 4.41:	Cross sectional flow visualization of various flip chip design during encapsulation	95
Figure 4.42:	Flow visualization of MUF flip chip package due to rheological effect (a) $\alpha = 0.01$ and (b) $\alpha = 0.05$	98
Figure 4.43:	EMC flow front length with different rheological effect in various flip chip package design	99
Figure 4.44:	Velocity versus Z-direction of cavity package with different degree of conversion	100
Figure 4.45:	Shear rate versus Z-direction of cavity package with different degree of conversion	101
Figure 4.46:	Viscosity versus Z-direction of cavity package with different degree of conversion	102
Figure 4.47:	Schematic diagram of EMC flow inside the multi flip chip package	103
Figure 4.48:	Flow visualization of EMC at solder bump of flip chip package during encapsulation	105
Figure 4.49:	First Collision Point and Merging Angle position in weld line prediction formation	106

LIST OF ABBREVIATIONS

		Page
IC	Integrated Circuit	xiii
CSP	Chip Scale Package	xiii
MUF	Molded Underfill	xiii
VOF	Volume of Fluid	xiii
EMC	Epoxy Molding Comppound	xiii
THM	Through-Hole Mount package	1
SMT	Surface Mount Package	1
FCBGA	Flip Chip Ball Grid Arrays	2
WBGA	Wire Bond Ball Grid Arrays	2
CUF	Capillary Underfill	3
NUF	No-flow Underfill	3
CAE	Computer-Aided Engineering	6
FEA	Finite Element Analysis	6
CFD	Computational Fluid Dynamics	6
MBD	Multibody Dynamics	6
FDM	Finite Different Method	6
FEM	Finite Element Method	6
FVM	Finite Volume Method	6
TQFP	Thin Quad Flat Package	10
TSOP	Thin Profile Small Outline Package	10

MAP	Mold array Package	10
S-CSP	Stacked-Chip Scale Package	10
CTE	Coefficient of Thermal Expansion	11
PUF	Pressurize Underfill	12
GNF	Generalized Newtonian Fluid	18
ICM	Injection Compression Molding	20
CIM	Conventioanal Injection Molding	20
EWLP	Embedded Wafer Level Package	20
PBGA	Plastic Ball Grid Array	21
TSV	Through Silicon Via	21
FSI	Fluid/Structure Interaction	22
DMA	Dynamic Mechanical Analysis	23
RTM	Resin Transfer Molding	23
CAD	Computer Assisted Design	24
PP	Polypropene	28
FCR	Flip Chip Region	64
FPR	Flip Passage Region	64
FCP	First Collision Point	102

LIST OF SYMBOLS

T_g	Glass transition temperature
V	Velocity vector
u	Fluid velocity component in x-direction
v	Fluid velocity component in y-direction
w	Fluid velocity component in z-direction
P	Pressure
T	Temperature
c_p	Specific Heat
k	Thermal Conductivity
ΔH	Exothermic heat
K	Flow consistency index
n	Power Law index
B	Exponential fitted constant
T_b	Temperature fitted constant
c_1	Fitting Constant
c_2	Fitting Constant
F	Front advancement parameter
T_m	Mold Temperature
T_{in}	Temperature at inlet
(x, y, z)	Cartesian coordinates

ρ	Density
η	Viscosity
$\dot{\gamma}$	Shear rate
$\dot{\alpha}$	Conversion rate
η_o	Zero shear rate viscosity
τ^*	A parameter that describes the transition region between power law region and zero shear rate of the viscosity curve
α	Degree of Conversion

**ANALISIS BERANGKA SEMASA PROSES PENGKAPSULAN
DALAM ACUAN ISIAN BAWAH DENGAN PEMPAKEJAN FLIP CIP
BERGANDA**

ABSTRAK

Pada masa kini, teknologi pembungkusan litar bersepadu (IC) menjadi reka bentuk yang canggih di samping dapat mengekalkan kebolehpercayaan dan kualiti. Pakej skala cip flip (CSP) adalah salah satu daripada cip IC yang mempunyai wafer-tingkat yang dibungkus dengan bebola pateri sfera yang terletak di atas grid yang mana jaraknya telah ditentukan di antara cip. Untuk membungkusnya, acuan isian bawah (MUF) telah digunakan dan ia merupakan proses yang lebih mudah dan lebih cepat. Walau bagaimanapun, aliran sebatian acuan epoksi (EMC) yang tidak konsisten semasa pengkapsulan yang lebih mudah terdedah kepada corak pengisian yang tidak seimbang, pengisian tidak lengkap dan kekosongan dalaman. Kerana itu, proses pengisian dan aliran EMC melalui flip cip sangat sukar untuk digambarkan dengan eksperimen sebenar. Dalam kajian ini, pendekatan berangka telah digunakan untuk mengkaji proses pembungkusan flip cip dalam rerongga. Oleh itu, analisis berangka adalah pendekatan yang sesuai untuk digambarkan semasa proses pembungkusannya. Perisian ANSYS FLUENT pula telah digunakan untuk mensimulasi dan menganalisis fenomena aliran cecair dan akibatnya. Teknik jumlah cecair (VOF) telah digunakan untuk memvisualisasi aliran MUF di rongga kosong dan cip flip yg berganda telah dibentangkan. Kajian terhadap tingkah laku aliran EMC dalam model rheologi yang berbeza juga telah dijalankan. Model Castro Macosko telah dikenal pasti sebagai model reologi yang terbaik untuk mempelajari perilaku aliran kerana ia telah mempertimbangkan kesan pengawetan dan tahap penukaran. Analisis berangka diteruskan pada kesan susunan flip cip. Susunan

berganda tiga cip flip mempunyai aliran pengurangan yang lebih tinggi dan peratusan jumlah udara terbentuk terbesar semasa pembungkusan. Hubungan kesan rheologi ke atas reka bentuk flip cip telah dikaji dengan sewajarnya. Perubahan kesan rheologi dan reka bentuk susun telah mempengaruhi sifat-sifat EMC seperti halaju, kadar ricih dan kelikatan.

NUMERICAL ANALYSIS DURING ECAPSULATION PROCESS OF MOLDED UNDERFILL WITH MULTI FLIP CHIP PACKAGE

ABSTRACT

Nowadays, the technology of Integrated Circuit (IC) packaging has become a sophisticated design in addition to maintaining reliability and quality. Flip Chip Scale Package (CSP) is one of the IC chips which has a wafer-level packaged with spherical solder bump located on a grid with a pre-defined pitch between chip. In order to package it, Molded Underfill (MUF) was used which was an easier and faster process. However, the inconsistent flow of Epoxy Molding Compound (EMC) during encapsulation was more susceptible to unbalanced filling pattern, incomplete filling and internal void. Therefore, the EMC filling and flow through flip chip is very hard to visualize with actual experiment. In this study, the numerical approaches were used to study the encapsulation process of multi flip chip in the cavity. Thus, the numerical analysis is an appropriate approach to visualize during the encapsulation process. ANSYS FLUENT was used to simulate and analyze the fluid flow phenomena and consequences. The volume of fluid (VOF) technique was used for visualization of flow front. The flow visualization of MUF in the empty cavity and multi flip chip were presented. The flow behavior of EMC in different rheology models have been conducted. The Castro Macosko model has been identified as the best model to study flow behavior since it has considered the curing effect and degree of conversion. The numerical analysis is continued on stacking effect of flip chip. Triple stacked multi flip chip was found to have high retardation flow and large volume percentage during encapsulation. The relationship of rheological effect on stacking design of flip chip were studied accordingly. Changes in rheological effect

and stacking design have influenced the EMC properties such as velocity, shear rate and viscosity.

CHAPTER ONE

INTRODUCTION

1.1 Overview of Integrated Circuit Packaging

Integrated Circuit (IC) packaging is a final manufacturing process of semiconductor device which encapsulated with semiconducting material in order to prevent from physical damage. Higher demand by electronic industries for IC package in order to get high performance required a great design to maintain its reliability and quality of electronic devices (Wan et al., 2007). Development of IC package is dynamic technology that always need an improvement in design and has multi function. There are many types of IC package have been produce to fill the industrial needs.

IC package can be categorised into three type of packages, which are through-hole mount package (THM), surface mount package (SMT) and chip scale package (CSP). Figure 1.1 shows the trend of IC package change from through-hole mount package to chip scale package (Anon, 2001). The design of IC package evolve from large design to smaller design and the evolution of their trend also grow same as the technology devices nowadays. Recently, CSP become one of the popular IC package because of its trend toward smaller, lighter and thinner where it meets application's demand (Khor & Abdullah, 2013). The combination of its performance and its small size make it become ideal solution for electronic manufacturing.

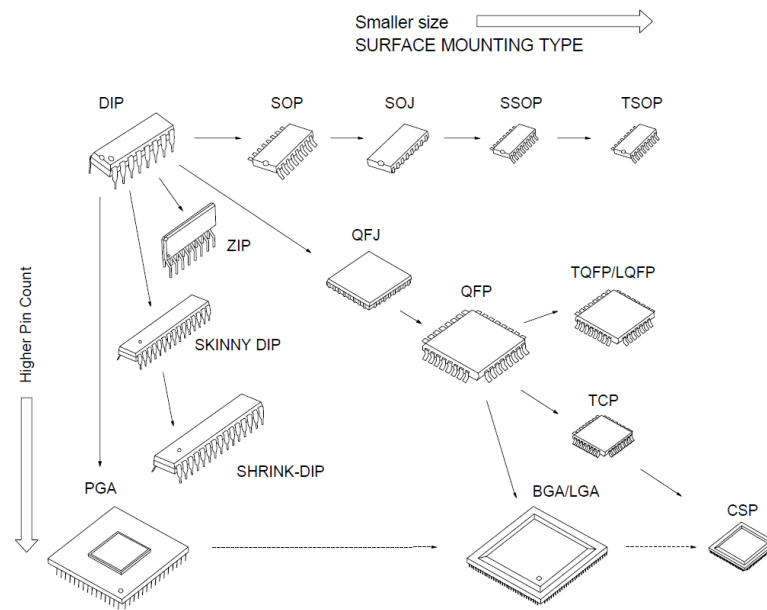


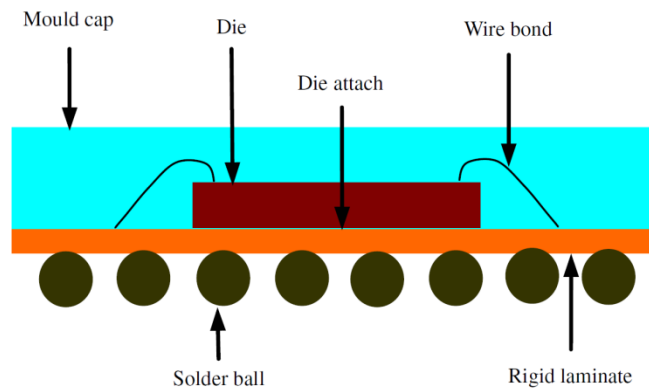
Figure 1.1 : Trend of IC Package (Anon, 2001)

CSP is a single die which its package is 1.2 times the size of the die and it is an evolution of surface mount package. There are many types of CSP and the most popular in CSP are flip chip ball grid arrays (FCBGA) and wire bond ball grid arrays (WBGA). Figure 1.2 (a) shows the cross section of WBGA and it consists of the interconnection between substrate and die using wire. The die attaches directly to the substrate and the active surface of the die faces upward, then it is looped and bonded to the substrate. Since the current trend is to get smaller and higher input/output, it can be one of the challenges to the electronic industry. It needs more wire to be bonded in the package. Hence, the industry will face a production problem and increase the cost.

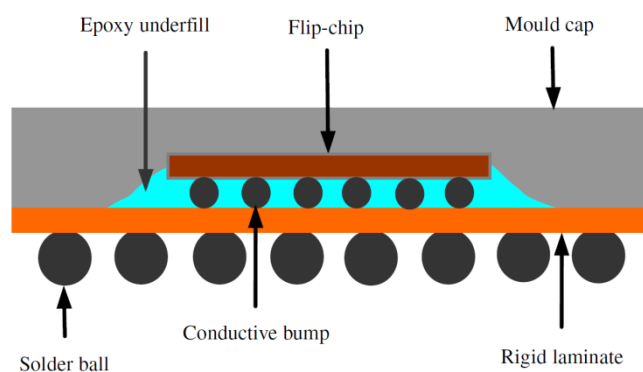
The flip chip technology is introduced to tackle this problem by the die is connected to substrate with conductive bump (Wan et al., 2007). Figure 1.2 (b) shows the cross section of FCBGA package where the interconnection between chip and

substrate by solder bump. The active surface of chip is flipped and attached to the solder bump, which is attached to the substrate.

In flip chip technology, the gap between substrate and chip is underfilled with highly filled epoxy system. Underfill is one of important part in flip chip package where it provides a good reliability and quality. It can be classified into capillary underfill (CUF), no-flow underfill (NUF) and molded underfill (MUF) (Wong & Wong, 1999; Joshi et al., 2010).



(a)



(b)

Figure 1.2: (a) WBGA (b) FCBGA (Wan et al., 2007)

1.2 Molded Underfill of Flip Chip Package

Molded underfill (MUF) is a process used in IC packaging to fill the gap between the chip and substrate, and encapsulate the whole chip (over molding). Figure 1.3 shows the cross section of single MUF of flip chip package. Increased functionality requirement and advance in packaging technology made MUF is the right choice for alteration of flip chip design. The advantages of using MUF are lower material cost, save time production and provide excellent reliability for advanced electronic application (Chen et al., 2013). Besides that, MUF process is simple and faster compared to CUF (Joshi et al., 2010). Epoxy Mold Compound (EMC) is a solid epoxy based resin with fillers that has been used as a molded underfill material for encapsulation in order to protect the die and the solder bump from the stress and temperature effect (Khor et al., 2011). Figure 1.4 show EMC flow through the flip chip package during encapsulation process.

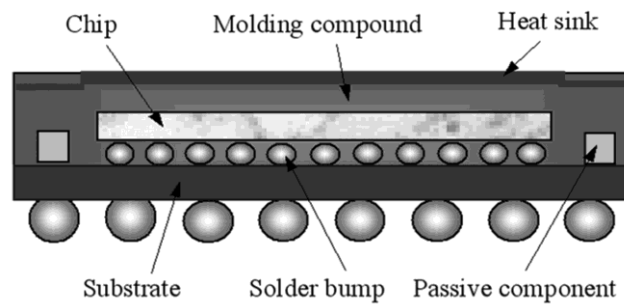


Figure 1.3: Cross section of Single Molded Underfill of Flip Chip Package

(Chen, 2008)